

Title (en)  
STATION AND METHOD FOR MEASURING THE PARTICULATE CONTAMINATION OF A TRANSPORT CHAMBER FOR CONVEYING AND ATMOSPHERICALLY STORING SEMICONDUCTOR SUBSTRATES

Title (de)  
STATION UND VERFAHREN ZUR MESSUNG DER PARTIKELKONTAMINATION EINER TRANSPORTKAMMER ZUM FÖRDERN UND ATMOSPHERISCHEN LAGERN VON HALBLEITERSUBSTRATEN

Title (fr)  
STATION ET PROCEDE DE MESURE DE LA CONTAMINATION EN PARTICULES D'UNE ENCEINTE DE TRANSPORT POUR LE CONVOYAGE ET LE STOCKAGE ATMOSPHERIQUE DE SUBSTRATS SEMI-CONDUCTEURS

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Abstract (en)  
[origin: WO2014083152A1] The present invention relates to a method for measuring the particulate contamination of a transport chamber for conveying and atmospherically storing semiconductor substrates, used in a measuring station. The measurement method comprises: a step in which the measurement module (5) is coupled to a rigid enclosure (2), defining a first measurement space (V1) between the measurement interface enclosure (16) and the rigid enclosure (2) coupled such as to carry out a measurement of the contamination of the inner walls of the rigid enclosure (2), and a step in which the door (3) is coupled to the measurement module (5), defining a second measurement space (V2) between said measurement surface (22) and the facing door (3), in order to carry out a measurement of the contamination of the door (3). The invention further relates to an associated measurement station.

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